

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q85281

Yuji EGUCHI, et al.

Appln. No.: 10/518,013

Group Art Unit: 1792

Confirmation No.: 1952

Examiner: Binh X. Tran

Filed: December 14, 2004

For:

OXIDE FILM FORMING METHOD AND OXIDE FILM FORMING APPARATUS

AMENDMENT UNDER 37 C.F.R. § 1.116

MAIL STOP AF

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated October 23, 2009, please amend the aboveidentified application as follows on the accompanying pages.

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